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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent of:

Saini et al.

Application Serial No.: 10/799,836

Filed: 03/12/2004

For: Compact Microcolumn for
Automated Assembly

§ Customer Number: 000027683
§ Issued Patent No.: 7,081,630
§ Issued: 07/25/2006
§ Docket Number: 34003.110

SUBMISSION OF DOCUMENTS UNDER 37 CFR 1.501

Commissioner For Patents
PO Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The undersigned herewith submits in the above-identified patent the references (including a copy of the non-patent literature and foreign patent documents) listed on the attached PTO-1449 form. These documents are pertinent and applicable to the patent and may have a bearing on the patentability thereof on the basis that the documents were cited in pending United States patent applications.

Respectfully submitted,

Dated: 3 AUGUST 2006
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R115125.1

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I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, PO Box 1450, Alexandria, VA 22313-1450 on <u>8-3-06</u>	
<u>Gayle Conner</u>	
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In place of PTO-1449 Form	U. S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			<i>Complete if Known</i>			
INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>						Application Number	10/799,836 (USP 7,081,630)
						Filing Date	03/12/2004 (Issued: 07/25/2006)
						Applicant(s)	Saini et al.
						Art Unit	2881
						Examiner Name	Smith, Johnnie L.
CSHEET	1	OF	3	Attorney Docket Number 34003.110			

U. S. PATENT DOCUMENTS				
Examiner's Initials	Cite No.	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
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Examiner Signature	Date Considered
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.

R115126.1

Customer No. 000027683

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SHEET	2	OF	3	Attorney Docket Number	

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SHEET

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Number 34003.110

U. S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

Examiner's Initials	Cite No.	Foreign Patent Document (Country Code - Number - Kind)	Publication Date MM-DD-YYYY	Patentee or Applicant of Cited Document	Translation Y/N
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		JP05166973	07/1993	Mitsubishi Electric Corp.	English Abstract
		JP06061691	03/1994	Matsushita Electric Ind. Co. Ltd.	English Abstract
		WO 9713981	04/1997	Minnesota Mining & Mfg. Co.	
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NON-PATENT LITERATURE DOCUMENTS

Examiner's Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item, date, page(s), volume-issue number(s), publisher, city/country where published
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PTO-1449
Form

U. S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

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SHEET

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